Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

- 1. (Currently Amended) A semiconductor laser chip, comprising:
- a ridge structure <u>disposed between channels formed on</u>
 [[at]] a junction surface of the laser chip; and
- a plurality of pads only on non-active areas of the junction surface, wherein the plurality of pads protrude beyond an edge of the ridge structure.
- 2. (Original) The laser chip of claim 1, further comprising:
- a substrate comprising the junction surface and a mounting surface, wherein the laser chip is capable of being mounted onto another surface at the mounting surface.
- 3. (Currently Amended) The laser chip of claim 1, wherein the plurality of pads are configured to abut a manufacturing tool can abut the plurality of pads without the manufacturing tool abutting the ridge structure.
- 4. (Currently Amended) The laser chip of claim 3, wherein [a vacuum force at which the manufacturing tool abuts] the

plurality of pads are configured to abut the manufacturing tool having a suitable vacuum force is optimized.

- 5. (Currently Amended) The laser chip of claim 1, wherein the plurality of pads are configured to function functions as reference reticles for the manufacturing tool.
- 6. (Original) The laser chip of claim 1, wherein the ridge structure protrudes beyond an edge of the junction surface.
- 7. (Currently Amended) The laser chip of claim 1, further comprising a plurality of contacts on active areas of the junction surface, wherein the plurality of pads [[is]] are disconnected from the plurality of contacts.
- 8. (Original) The laser chip of claim 1, wherein at least one of the plurality of pads comprises a metallic material.
- 9. (Original) The laser chip of claim 1, wherein at least one of the plurality of pads comprises a non-metallic material.
- 10. (Currently Amended) The laser chip of claim 1, wherein the laser chip is configured for operation functions—at a frequency of approximately 1 GHz or higher.
- 11. (Original) The laser chip of claim 1, further comprising a source current modulated in time.

- 12. (Currently Amended) A method for providing a semiconductor laser chip, comprising the steps of:
- (a) providing a ridge structure at a junction surface of the laser chip between channels formed on the junction surface; and
- (b) providing a plurality of pads only on non-active areas of the junction surface, wherein the plurality of pads protrude beyond an edge of the ridge structure.
- 13. (Original) The method of claim 12, wherein the providing step (a) comprises:
- (al) providing a substrate comprising the junction surface and a mounting surface, wherein the laser chip is capable of being mounted onto another surface at the mounting surface.
 - 14. (Original) The method of claim 12, further comprising:
- (c) holding the laser chip using a tool, wherein the tool abuts the plurality of pads without abutting the ridge structure.
 - 15. (Original) The method of claim 14, further comprising:
- (cl) optimizing a vacuum force at which the tool abuts the plurality of pads.
- 16. (Currently Amended) The method of claim 14, wherein the plurality of pads <u>functions</u> <u>function</u> as reference reticles for the tool.

- 17. (Original) The method of claim 12, wherein the ridge structure protrudes beyond an edge of the junction surface.
- 18. (Currently Amended) The method of claim 12, further comprising:
- (c) providing a plurality of contacts on active areas of the junction surface, wherein the plurality of pads [[is]] are disconnected from the plurality of contacts.
- 19. (Original) The method of claim 12, wherein at least one of the plurality of pads comprises a metallic material.
- 20. (Original) The method of claim 12, wherein at least one of the plurality of pads comprises a non-metallic material.
- 21. (Currently Amended) The method of claim 12, wherein the laser chip <u>functions</u> <u>operates</u> at a frequency of approximately 1 GHz or higher.
- 22. (Original) The method of claim 12, further comprising a source current modulated in time.
- 23. (Currently Amended) A high-speed, directly modulated semiconductor ridge waveguide laser, comprising:
 - a substrate comprising a junction surface;

a ridge structure <u>disposed between channels formed on</u> [[at]] the junction surface, wherein the ridge structure protrudes beyond an edge of the junction surface; and

a plurality of pads on the junction surface, wherein the plurality of pads protrude beyond an edge of the ridge structure, wherein the plurality of pads reside only on non-active areas of the junction surface, wherein the plurality of pads are configured to abut a manufacturing tool can abut the plurality of pads without the manufacturing tool abutting the ridge structure.